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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10017389	12 18 2001	257		2811	

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**CONTINUING DATA VERIFIED: *✓* *✓*

** FOREIGN APPLICATIONS VERIFIED: *✓* *✓*
JAPAN 2000-386624 12/20/2000

PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>
Foreign priority claimed 35 USC 119 conditions met Verified and Acknowledged by Examiner's initials		✓ yes <input type="checkbox"/> no ✓ yes <input type="checkbox"/> no
ATTORNEY DOCKET NO 740819-720		
TITLE : Method for fabricating semiconductor, method for fabricating semiconductor substrate, and semiconductor light emitting device		

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Assistant Examiner	
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drwg.	Figs.Drwg.
TERMINAL DISCLAIMER		Primary Examiner	
		Application Examiner	
PREPARED FOR ISSUE			
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